

FIG. 1A

INTRODUCTION OF Ni ELEMENT

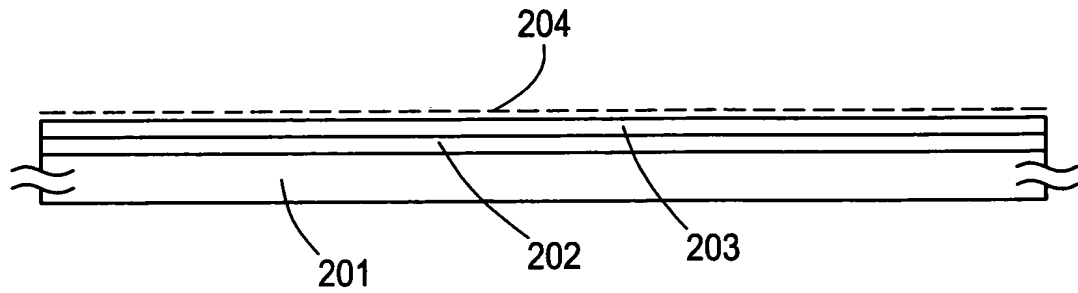


FIG. 1B

CRYSTALLIZATION BY THERMAL PROCESSING

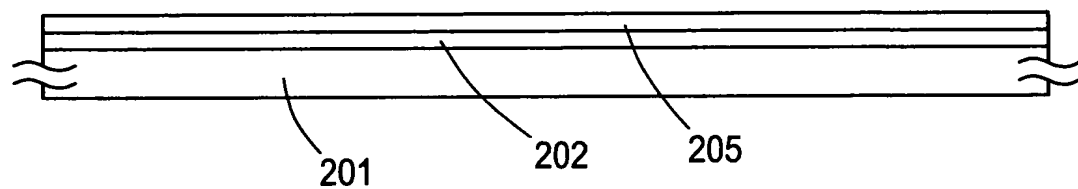


FIG. 1C

FORMATION OF THERMAL OXIDE FILM



FIG. 1D

REMOVAL OF THERMAL OXIDE FILM

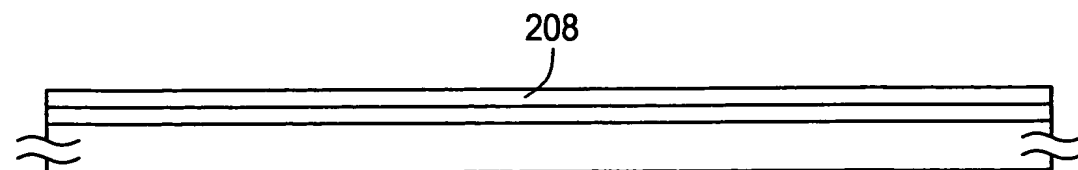


FIG. 2A

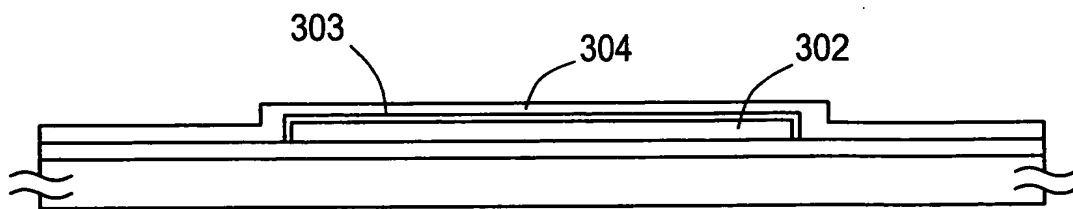


FIG. 2B

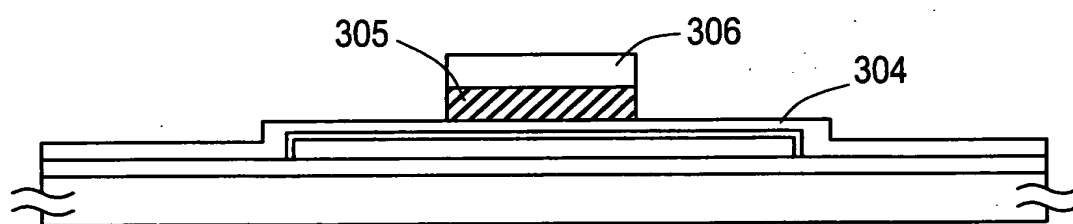


FIG. 2C

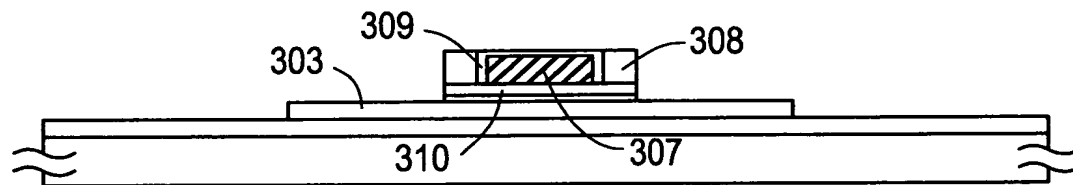


FIG. 2D

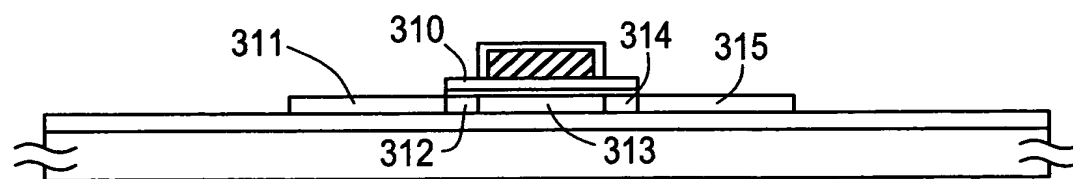


FIG. 2E

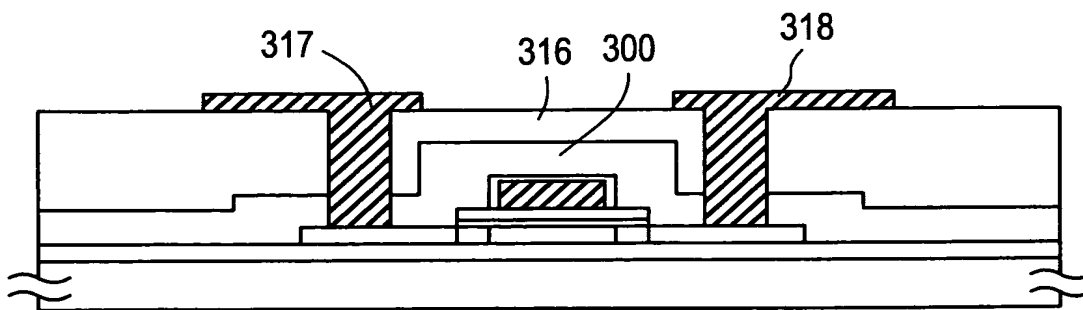


FIG. 3

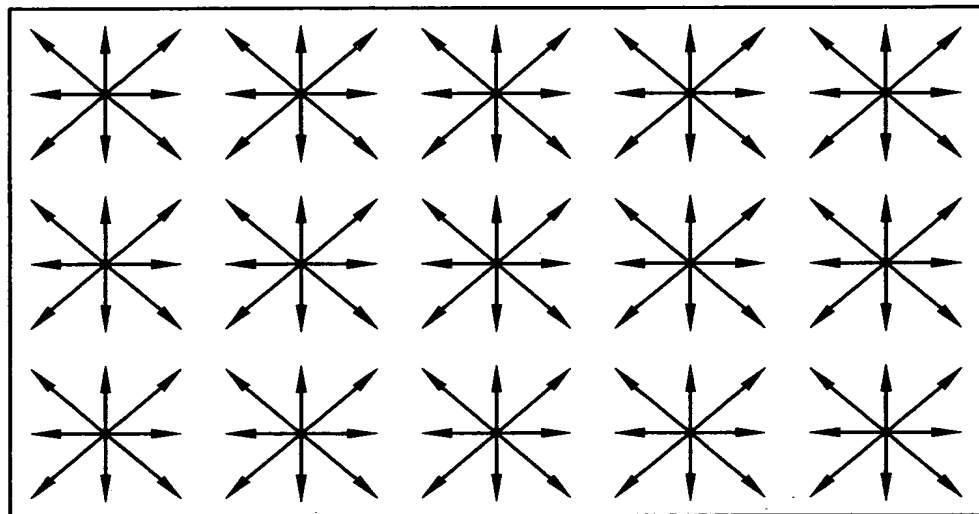


FIG. 4A

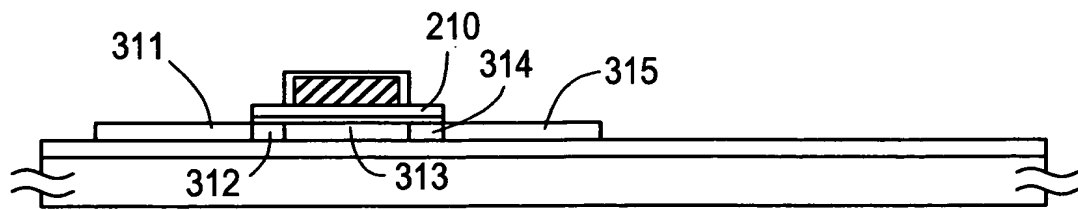


FIG. 4B

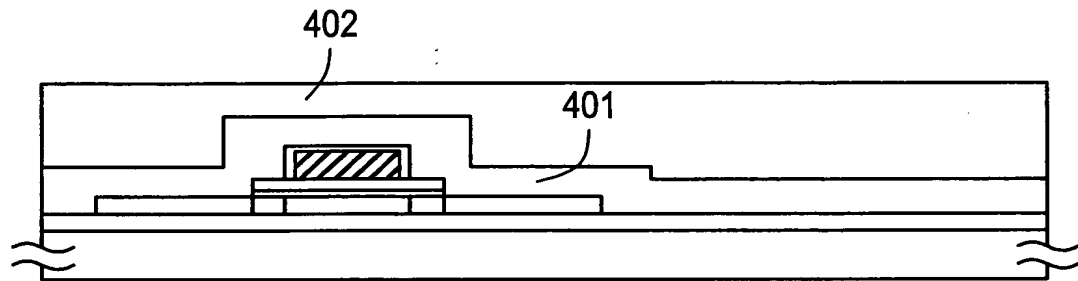


FIG. 4C

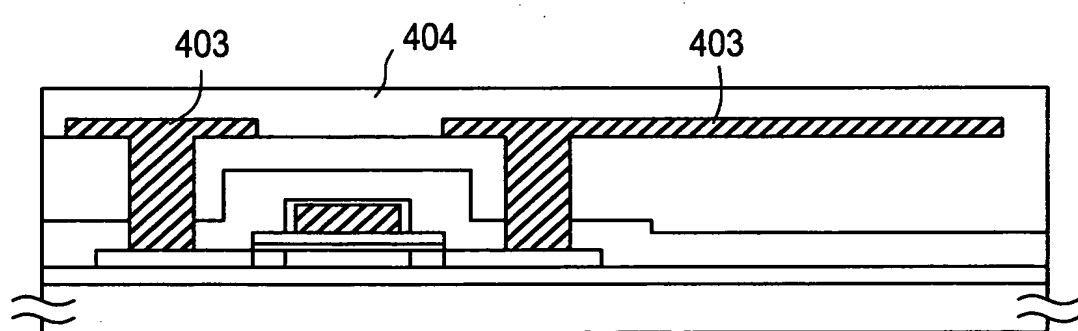


FIG. 4D

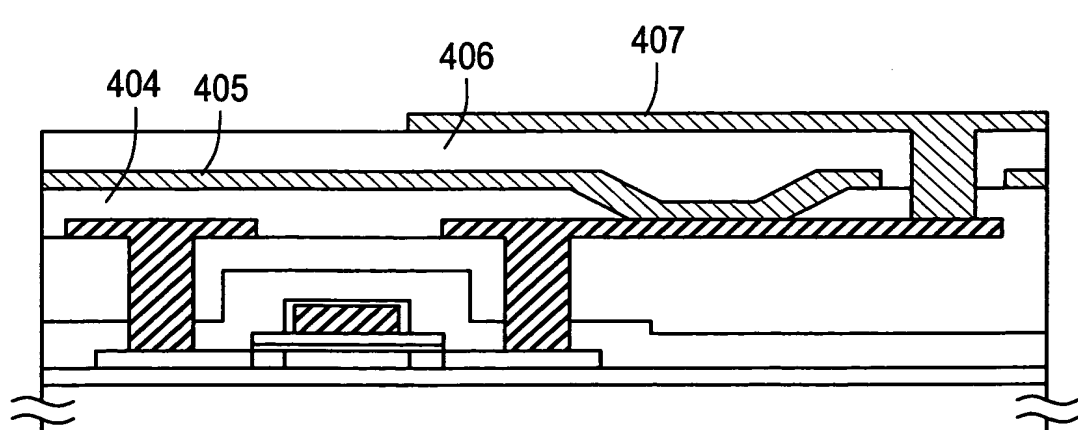


FIG. 5A

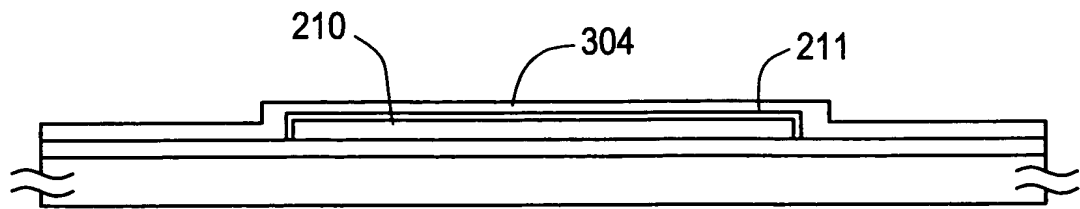


FIG. 5B

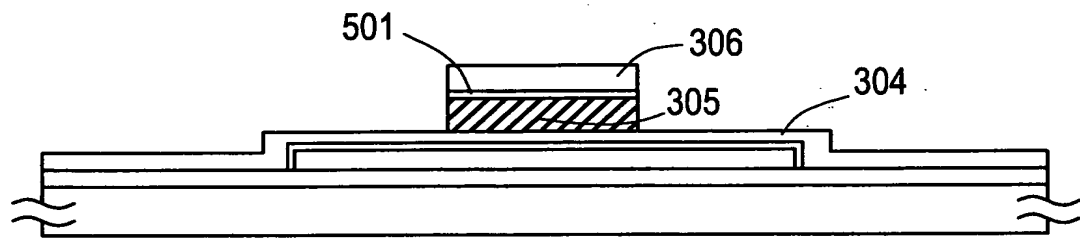


FIG. 5C

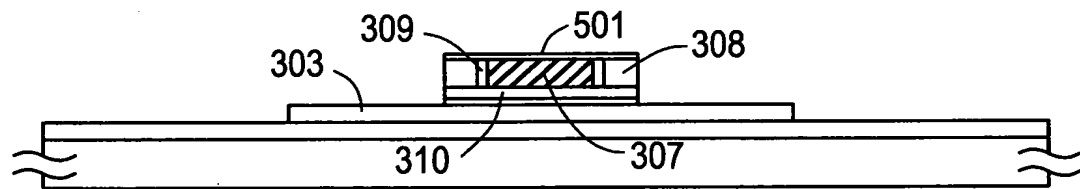


FIG. 5D

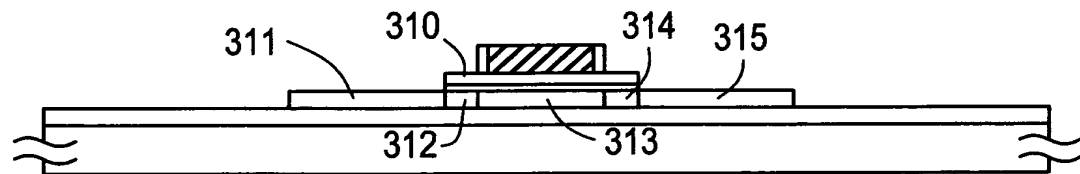


FIG. 5E

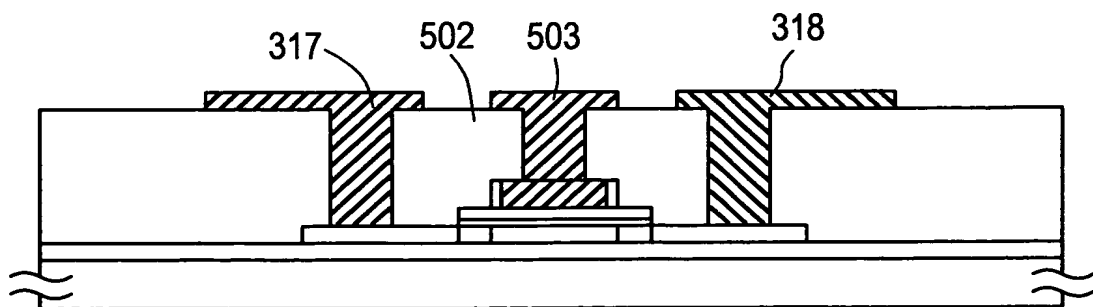
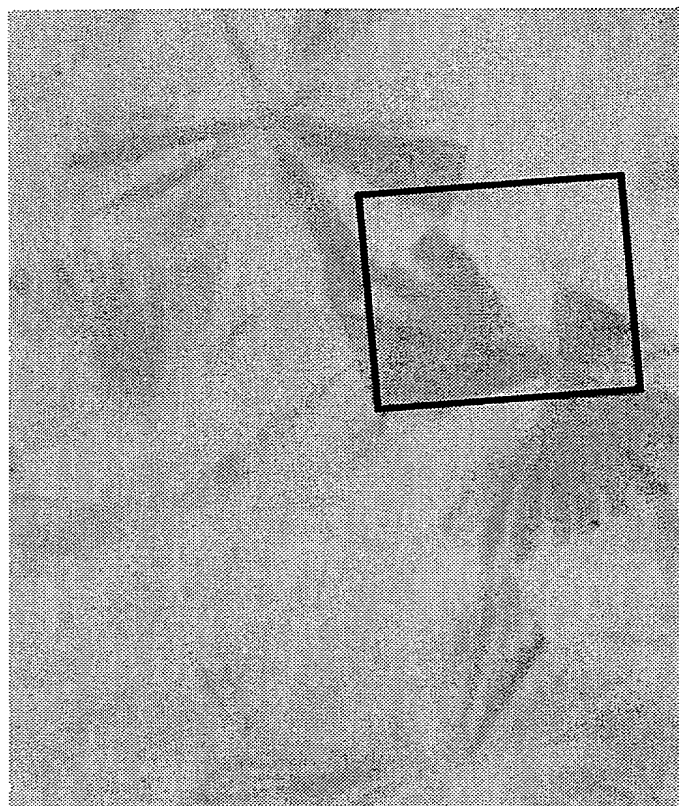


FIG. 6



100 μm

FIG. 7

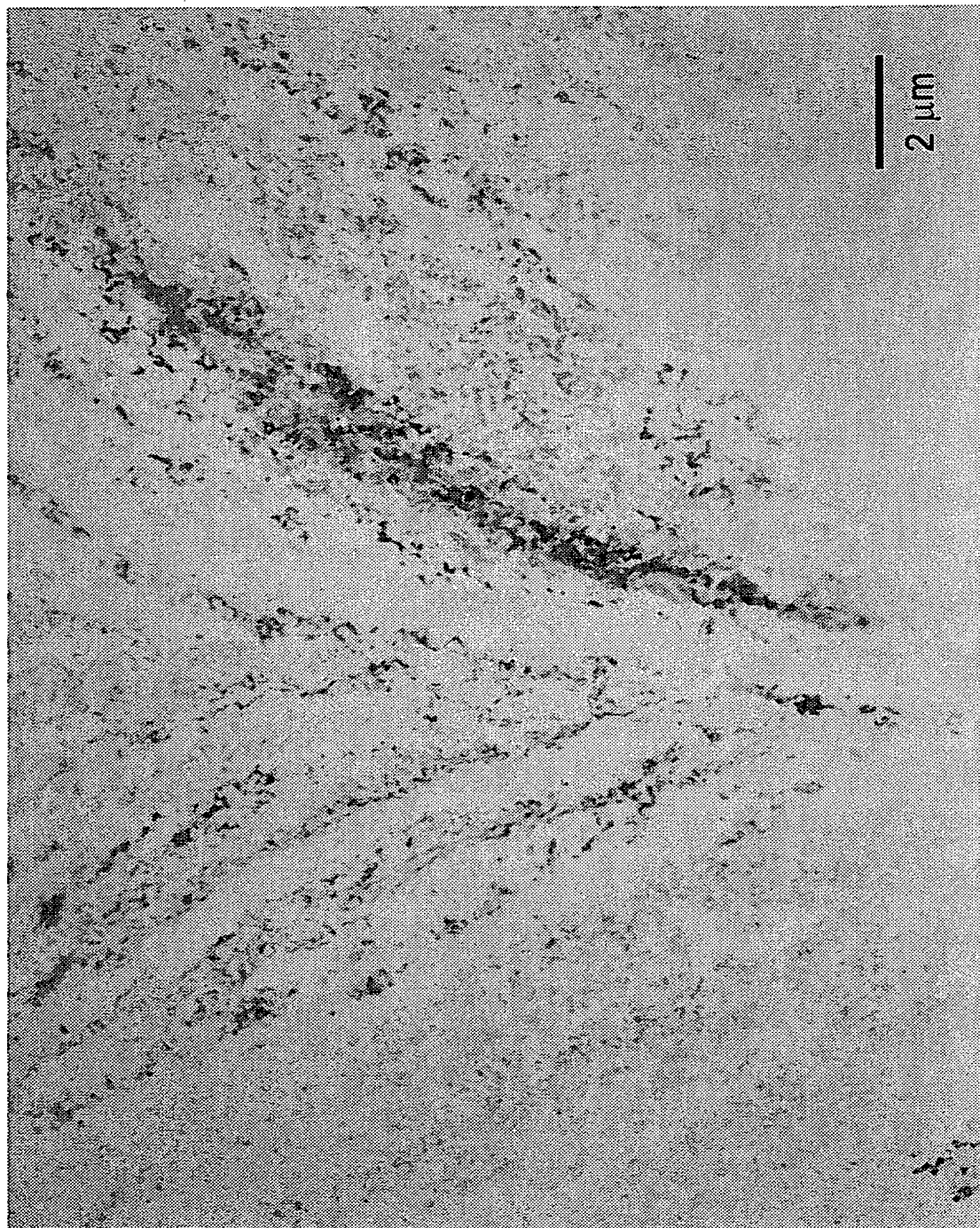
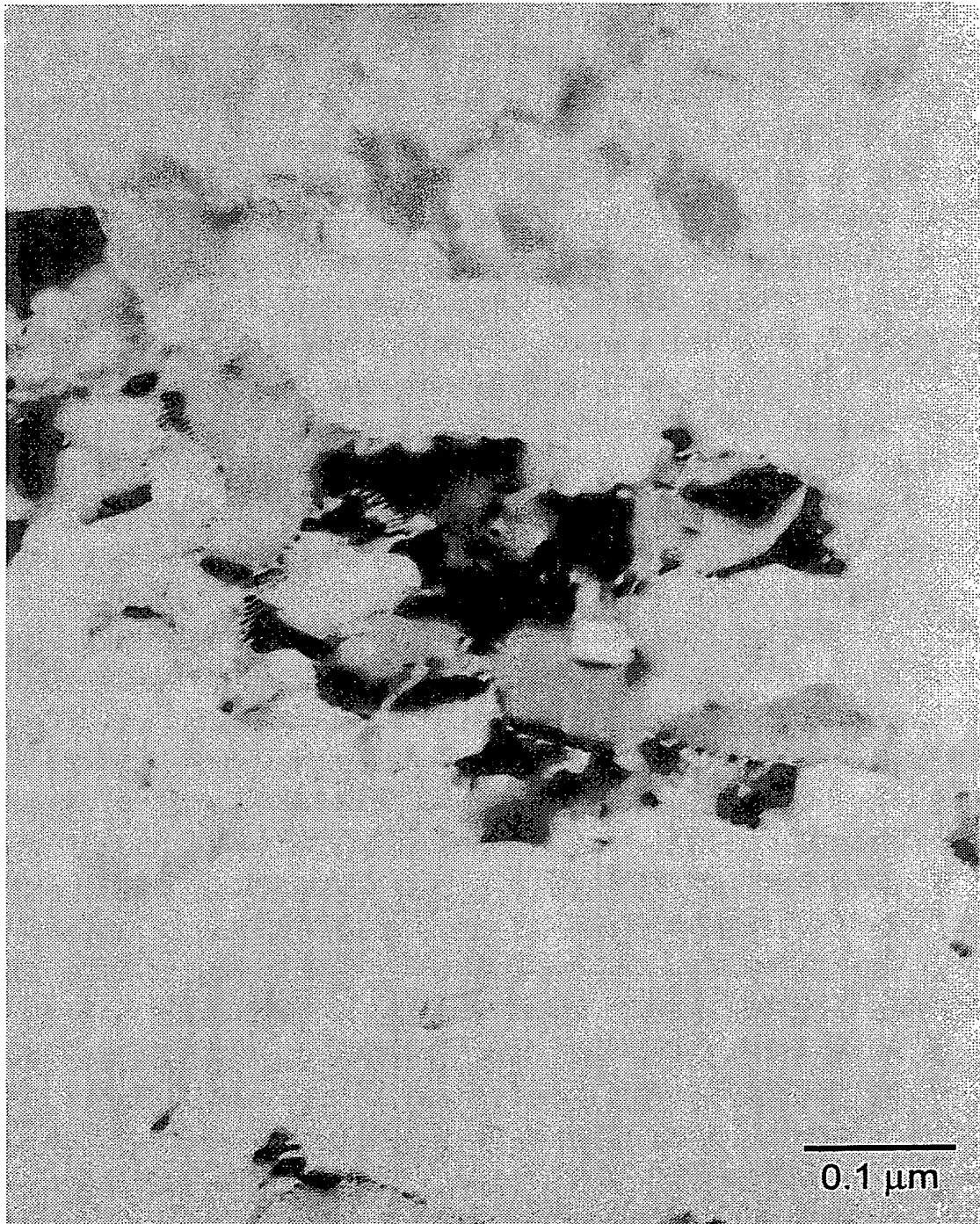


FIG. 8



BEST AVAILABLE COPY

FIG. 9A

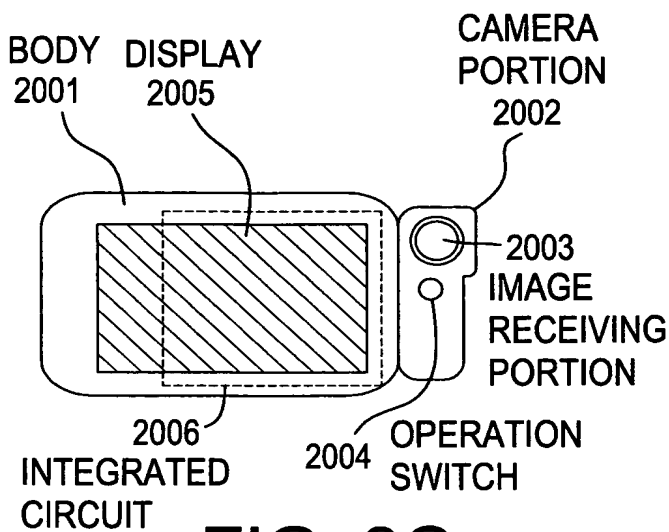


FIG. 9B

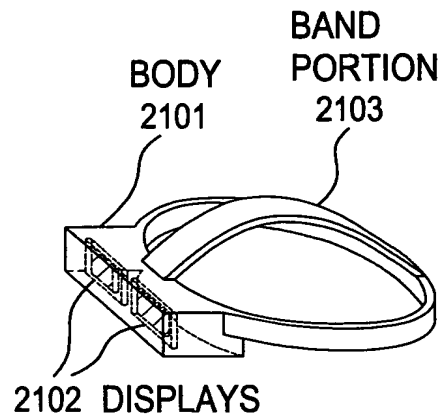


FIG. 9C

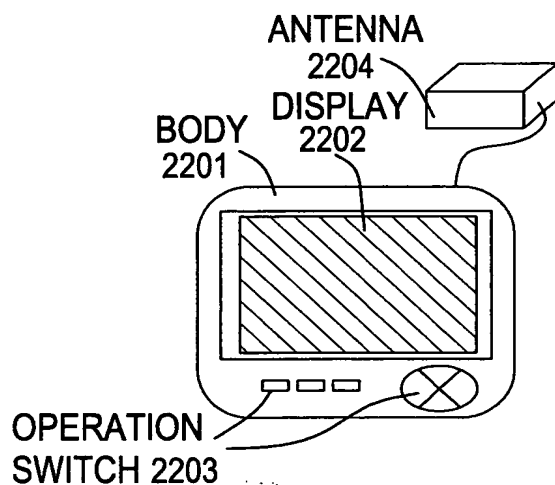


FIG. 9D

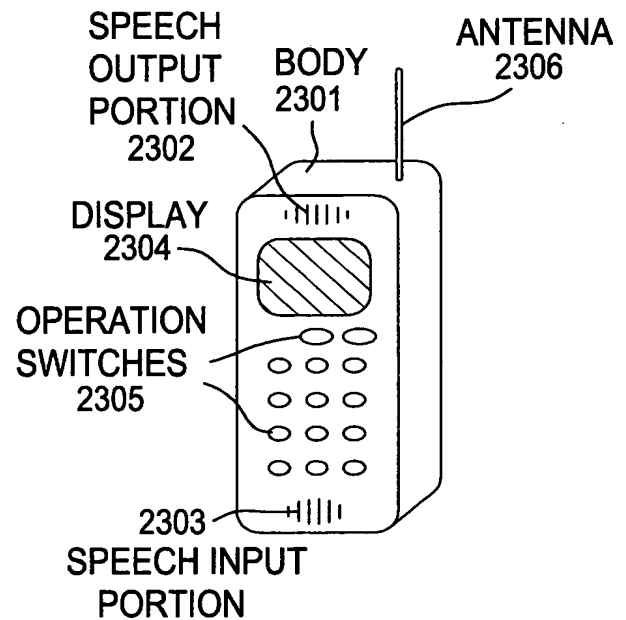


FIG. 9E

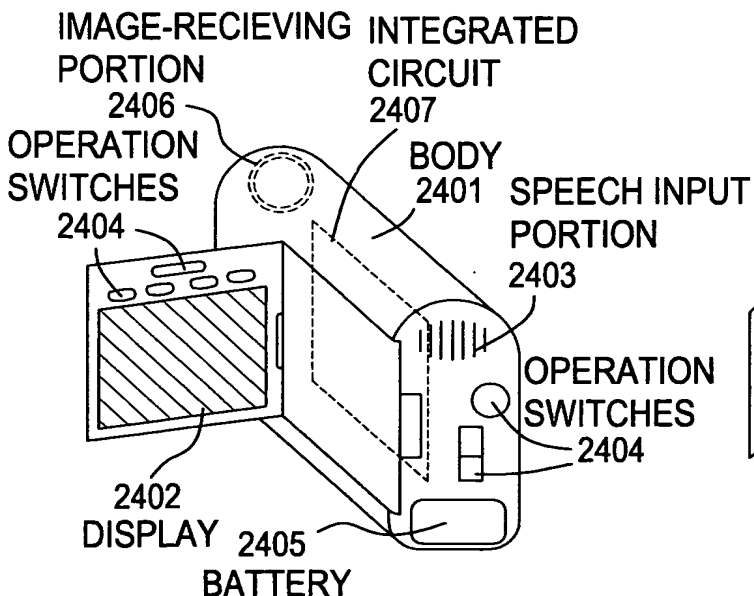


FIG. 9F

